EUROPEAN PATENT OFFICE

Patent Abstracts of Japan

PUBLICATION NUMBER

2001040293

PUBLICATION DATE

13-02-01

APPLICATION DATE

03-08-99

APPLICATION NUMBER

: 11220429

APPLICANT: JSR CORP;

INVENTOR: SHIMOKAWA TSUTOMU;

INT.CL.

: C09D201/00 C08F299/02 C08G 10/02

C08L 61/18 C09D161/18 G03F 7/11

H01L 21/027

TITLE

ANTIREFLECTION FILM FORMING

COMPOSITION

ABSTRACT: PROBLEM TO BE SOLVED: To obtain the subject composition capable of forming a resist pattern having a high antireflection effect, not causing an inter mixing, having excellent resolution, accuracy, etc. by including a polymer containing a bifunctional group shown by a specific chemical structure and a solvent.

> SOLUTION: This composition comprises a polymer containing a bifunctional group of the formula (R1 is a monovalent atom or a monofunctional group; n is 0-4; plural R1 groups may be the same or different when n is 2-4; R2 and R3 are each a monovalent atom or a monofunctional group), a solvent such as ethylene glycol monomethyl ether, etc., (the amount of the solvent mixed is an amount to make the solid concentration of the obtained composition 0.1-50 wt.%) and preferably a curing agent such as tolylene diisocyanate, etc. The polymer is obtained, for example, by a condensation reaction between an acenaphthylene and an aldehyde.

COPYRIGHT: (C)2001,JPO